

L Number	Hits	Search Text	DB	Time stamp
1	28	platform with base with stage with support	USPAT	2004/05/10 10:34
2	42	precision adj stage with (wafer or semiconductor)	USPAT	2004/05/10 10:51
3	0	active adj support with pneumatic adj support with platform	USPAT	2004/05/10 10:37
4	0	active adj support with pneumatic adj support	USPAT	2004/05/10 10:37
5	0	voice adj coil with pneumatic adj support	USPAT	2004/05/10 10:38
7	3	voice adj coil with support with platform	USPAT	2004/05/10 10:38
8	73	voice adj coil with (support or stage or platform) with air	USPAT	2004/05/10 11:23
9	0	lithography adj stage with vibration adj isolation	USPAT	2004/05/10 11:24
10	1	lithography adj stage with vibration	USPAT	2004/05/10 11:24
6	677	voice adj coil with support	USPAT	2004/05/10 12:04
11	0	pneumatic adj support with model	USPAT	2004/05/10 12:04
12	14	pneumatic with support with model	USPAT	2004/05/10 13:19
13	82	platform with support with model	USPAT	2004/05/10 12:13
14	1	lithography with (platform or stage) with model	USPAT	2004/05/10 13:19
15	3	lithography with (platform or stage) with model	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 13:20
16	348	position with (platform or stage) with model	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 12:36
17	41	11-114	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 13:20
18	28	11-114	USPAT	2004/05/10 13:21
19	844	(platform with base with stage with support) or (precision adj stage with (wafer or semiconductor)) or (active adj support with pneumatic adj support with platform) or (active adj support with pneumatic adj support) or (voice adj coil with pneumatic adj support) or (voice adj coil with support) or (voice adj coil with support with platform) or (voice adj coil with (support or stage or platform) with air) or (lithography adj stage with vibration adj isolation) or (lithography adj stage with vibration) or (pneumatic adj support with model) or (pneumatic with support with model) or (platform with support with model) or (lithography with (platform or stage) with model)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 13:22

20	844	(platform with base with stage with support) or (precision adj stage with (wafer or semiconductor)) or (active adj support with pneumatic adj support with platform) or (active adj support with pneumatic adj support) or (voice adj coil with pneumatic adj support) or (voice adj coil with support) or (voice adj coil with support with platform) or (voice adj coil with (support or stage or platform) with air) or (lithography adj stage with vibration adj isolation) or (lithography adj stage with vibration) or (pneumatic adj support with model) or (pneumatic with support with model) or (platform with support with model) or (lithography with (platform or stage) with model)	USPAT	2004/05/10 13:24
21	156	active adj vibration adj isolation	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 14:50
22	41	model\$5 with rough with fine	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:02
23	0	pneumatic adj support with air adj control adj vlave	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:03
24	0	pneumatic adj support with air with vlave	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:03
25	0	pneumatic adj support with vlave	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:03
26	0	pneumatic near support with vlave	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:03
27	0	pneumatic adj support with air adj control adj valve	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:04
28	10	pneumatic adj support with air with valve	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:05
29	35	pneumatic adj support with valve	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:08
30	36	avis with system	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:19

31	520	platform with stage with position	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:20
32	56	platform with stage with position with support	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:37
33	0	platform adj position with stage adj position	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:37
34	3425	platform with stage	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:37
35	238	platform with stage.ti.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 16:02
36	6290	model with matrix	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 16:04
37	28	active adj support with (stage or platform)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 16:38
38	3317	430/22,30.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 16:39
39	3493	355/53,55.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 16:40
40	1473	248/550,638.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 16:41